

| | Hits | Search Text |
|----|--------|--|
| 1 | 21466 | (mask or reticle) same (substrate or wafer) same align\$6 |
| 2 | 25948 | (mask or reticle or substrate or wafer or reference or alignment) near3 mark |
| 3 | 4457 | S1 and S2 |
| 4 | 369 | (align\$6) with (numerical near aperture) |
| 5 | 10603 | (lens or projection) with (numerical near aperture) |
| 6 | 55 | ad<="20020716" and S6 |
| 7 | 55 | S3 and S4 and S5 |
| 8 | 50 | @ad<="20020716" and S6 |
| 9 | 57299 | (align\$5 or position\$3) near4 (mirror or reflector) |
| 10 | 105980 | (mask or reticle) same (substrate or wafer) |
| 11 | 9527 | (projection) near5 (mirror or reflector) |
| 12 | 957 | S10 and S11 and S12 |
| 13 | 720 | @ad<="20020716" and S13 |
| 14 | 20184 | (alignment or reference) near2 mark |
| 15 | 311 | S14 and S15 |
| 16 | 3509 | S15 with (mask or reticle) |
| 17 | 5411 | S15 with (substrate or wafer) |
| 18 | 231 | S17 and S18 and S14 |

PK
11/4/05